PATENT ASSIGNMENT

Electronic Version v1.1
Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	To correct the Correspondent's Name and Address due to an error in the Customer Number with the initial submission. Also, please correct the spelling of the inventor Ian Robson McFadyen.

CONVEYING PARTY DATA

Name	Execution Date
Alexander Bietsch	07/21/2004
Michael W. Chaw	06/15/2004
Ashok Lahiri	07/30/2004
Ian Robson McFadyen	06/16/2004
Bruno Michel	07/21/2004
Mark C. Thurber	07/21/2004

RECEIVING PARTY DATA

Name:	Hitachi Global Storage Technologies Netherlands B.V.
Street Address:	Locatellikade 1
Internal Address:	Parnassustoren
City:	1070 AZ Amsterdam
State/Country:	NETHERLANDS

PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	10692992

OP $40.00 10692992

CORRESPONDENCE DATA

Fax Number: (512)479-3923
Correspondence will be sent via US Mail when the fax attempt is unsuccessful.
Email: Michael.Noe@bracewellgiuliani.com
Correspondent Name: Bracewell & Giuliani LLP
Address Line 1: P.O. Box 61389
Address Line 2: Attn: Michael E. Noe, Jr.
Address Line 4: Houston, TEXAS 77208-1389

NAME OF SUBMITTER:	Michael E. Noe, Jr.

Total Attachments: 22
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page1.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page2.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page3.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page4.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page5.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page6.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page7.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page8.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page9.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page10.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page11.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page12.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page13.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page14.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page15.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page16.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page17.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page18.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page19.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page20.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page21.tif
source=HSJ920030074US1.ASSIGNMENT MATERIALS#page22.tif

Substitute Form PTO -1595	**RECORDATION FORM COVER SHEET** **PATENTS ONLY**	Patent Docket No. **HSJ920030074US1**

To The Honorable Commissioner of Patents and trademarks: Please record the attached original documents or copy thereof.

1. Name of conveying party(ies):	Execution date:
Alexander Bietsch	July 21, 2004
Michael W. Chaw	June 15, 2004
Ashok Lahiri	July 30, 2004
Ian Robson McFadyen	June 16, 2004
Bruno Michel	July 21, 2004
Mark C. Thurber	July 21, 2004

2. Name and address of receiving party(ies):

Hitachi Global Storage Technologies Netherlands B.V.
Locatellikade 1
1076 AZ Amsterdam
P.O. Box 75215
1070 AE Amsterdam
The Netherlands

3. Nature of conveyance:

√ Assignment ☐ Merger
☐ Security Agreement ☐ Change of Name
√ **Other (To correct the correspondent's address due to wrong Customer Number with initial submission)**

4. Application number(s) or patent number(s): Execution/Filing/Issue Date

☐ New Patent Application, execution date of application ______ Execution Date

√ Patent Application Number: **10/692,992** **October 24, 2003** Filing Date

☐ Patent Number: ______ ______ Issue Date

5. Name and address of party to whom correspondence concerning document should be mailed:

Customer Number 48583

Bracewell & Giuliani LLP
P.O. Box 61389
Houston, Texas 77208-1389

6. Total number of applications and patents involved: 1

7. Total fee (37 CFR 3.41)............. $40.00
☐ Enclosed Check
☐ Authorized to be charged to deposit account
☐ Authorized to charge any deficiency to deposit account

8. Deposit account number: ______

(Attach duplicate copy of this page if paying by deposit account)

DO NOT USE THIS SPACE

9. Statement and signature

To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is a true copy of the original document.

Betty J. Kirk ______ July 28, 2005
Name of Person Signing Signature Date

Total number of pages including cover sheet, attachments, and documents: **9**

Mail documents to be recorded with required cover sheet information to:
Commissioner of Patents & Trademarks, Box Assignments
Washington, D.C. 20231

Hitachi Global Storage Technologies Docket No.: HSJ920030074US1

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Mark C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) (1) ______, 2004; (2) 6/15, 2004;
(3) ______, 2004; (4) 6/16, 2004;
(5) ______, 2004; and (5) ______, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at ______ on ______, 2004.

______
Alexander Bietsch

(2) Signed at SAN JOSE on 6/15, 2004.

Michael W. Chaw

(3) Signed at ______________ on ______________, 2004.

____
Ashok Lahiri

(4) Signed at San Jose on June 16th, 2004.

Ian R McFadyen
Ian R. McFadyen

(5) Signed at ______________ on ______________, 2004.

____
Bruno Michel

(6) Signed at ______________ on ______________, 2004.

____
Mark C. Thurber

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) (1) 7/21, 2004; (2) ____, 2004; (3) ____, 2004; (4) ____, 2004; (5) ____, 2004; and (5) 7/21, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at Rüschlikon on July 21, 2004.

Alexander Bietsch

Alexander Bietsch

(2) Signed at ______________ on ______________, 2004.

____
Michael W. Chaw

(3) Signed at ______________ on ______________, 2004.

____
Ashok Lahiri

(4) Signed at ______________ on ______________, 2004.

____
Ian R. McFadyen

(5) Signed at Rüschlikon on 7/21, 2004.

Bruno Michel
Brino Michel

(6) Signed at ______________ on ______________, 2004.

____
Marc C. Thurber

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) **(1)** __________, 2004; **(2)** __________, 2004;
(3) 7/30, 2004; **(4)** __________, 2004;
(5) __________, 2004; and **(5)** __________, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at __________ on __________, 2004.

____

Alexander Bietsch

(2) Signed at ____________________ on ____________________, 2004.

____
Michael W. Chaw

(3) Signed at Cupertino on 7/30, 2004.

↑
city

Ashok Lahiri
Ashok Lahiri

(4) Signed at ____________________ on ____________________, 2004.

____
Ian R. McFadyen

(5) Signed at ____________________ on ____________________, 2004.

____
Brino Michel

(6) Signed at ____________________ on ____________________, 2004.

____
Marc C. Thurber

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Mark C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) **(1)** ______, 2004; **(2)** ______, 2004; **(3)** ______, 2004; **(4)** ______, 2004; **(5)** ______, 2004; and **(6)** 21 July, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands**, (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at ______ on ______, 2004.

______

Alexander Bietsch

(2) Signed at ______________________ on ______________________, 2004.

____

Michael W. Chaw

(3) Signed at ______________________ on ______________________, 2004.

____

Ashok Lahiri

(4) Signed at ______________________ on ______________________, 2004.

____

Ian R. McFadyen

(5) Signed at ______________________ on ______________________, 2004.

____

Bruno Michel

(6) Signed at El Salto, Jalisco, MEXICO on 21 July, 2004.

Mark C. Thurber

Mark C. Thurber

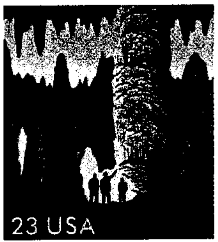
Received in the U.S.P.T.O.
In re Application of: **ALEXANDER BIETSCH ET AL.**
Application No. **10/787,476**
Filing Date: **FEBRUARY 26, 2004**
Attorney Docket No.: **HSJ920030074US1**
Title: **SYSTEM, METHOD AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING**

ENCLOSED HEREWITH:

1. This Return Receipt Postcard;
2. Notice of Recordation of Assignment with Patent Application No. and Filing Date (in duplicate); and
3. Executed Assignment

HITACHI Global Storage Technologies
Attorney Docket No.: **HSJ920030074US1**
Our File No. 041131.000032 - Mailed: August 17, 2004 - MEN:bk

Xc: HITACHI



Carlsbad Caverns National Park, NM

Bracewell & Patterson, L.L.P.
P.O. Box 61389
Houston, TX 77208-1389

Received in the U.S.P.T.O.
In re Application of: **ALEXANDER BIETSCH ET AL.**
Application No. **10/787,476**
Filing Date: **FEBRUARY 26, 2004**
Attorney Docket No.: **HSJ920030074US1**
Title: **SYSTEM, METHOD AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING**

ENCLOSED HEREWITH:

1. This Return Receipt Postcard;
2. Notice of Recordation of Assignment with Patent Application No. and Filing Date (in duplicate); and
3. Executed Assignment

HITACHI Global Storage Technologies
Attorney Docket No.: **HSJ920030074US1**
Our File No. 041131.000032 - Mailed: August 17, 2004 - MEN:bk

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Mark C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) **(1)** ______________, 2004; **(2)** 6/15, 2004;
(3) ______________, 2004; **(4)** 6/16, 2004;
(5) ______________, 2004; and **(5)** ______________, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at ______________ on ______________, 2004.

____
Alexander Bietsch

(2) Signed at SAN JOSE on 6/15, 2004.

Michael W. Chaw

(3) Signed at ______________ on ______________, 2004.

____

Ashok Lahiri

(4) Signed at San Jose on June 16th, 2004.

Ian R. McFadyen

(5) Signed at ______________ on ______________, 2004.

____

Bruno Michel

(6) Signed at ______________ on ______________, 2004.

____

Mark C. Thurber

Hitachi Global Storage Technologies Docket No.: HSJ920030074US1

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) (1) 7/21, 2004; (2) ________, 2004; (3) ________, 2004; (4) ________, 2004; (5) ________, 2004; and (5) 7/21, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at Rüschlikon on July 21, 2004.

Alexander Bietsch

Alexander Bietsch

(2) Signed at ____________ on ____________, 2004.

____
Michael W. Chaw

(3) Signed at ____________ on ____________, 2004.

____
Ashok Lahiri

(4) Signed at ____________ on ____________, 2004.

____
Ian R. McFadyen

(5) Signed at Rüschlikon on 7/21, 2004.

Bruno Michel
Brino Michel

(6) Signed at ____________ on ____________, 2004.

____
Marc C. Thurber

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) **(1)** ____________, 2004; **(2)** ____________, 2004;
(3) 7/30, 2004; **(4)** ____________, 2004;
(5) ____________, 2004; and **(5)** ____________, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at ____________ on ____________, 2004.

____

Alexander Bietsch

(2) Signed at ______________________ on ______________________, 2004.

____
Michael W. Chaw

(3) Signed at Cupertino on 7/30, 2004.

↑
City

Ashok Lahiri
____
Ashok Lahiri

(4) Signed at ______________________ on ______________________, 2004.

____
Ian R. McFadyen

(5) Signed at ______________________ on ______________________, 2004.

____
Brino Michel

(6) Signed at ______________________ on ______________________, 2004.

____
Marc C. Thurber

ASSIGNMENT

Whereas, I,

(1) Alexander Bietsch of Rueschlikon, Switzerland;

(2) Michael W. Chaw of San Jose, Santa Clara County, California;

(3) Ashok Lahiri of Mainz, Germany;

(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;

(5) Bruno Michel of Adliswil, Switzerland; and

(6) Mark C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) **(1)** ____________________, 2004; **(2)** ____________________, 2004; **(3)** ____________________, 2004; **(4)** ____________________, 2004; **(5)** ____________________, 2004; and **(6)** 21 July, 2004.

Whereas, **Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands,** (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

(1) Signed at ____________________ on ____________________, 2004.

____

Alexander Bietsch

(2) Signed at ______________________ on ______________________, 2004.

____

Michael W. Chaw

(3) Signed at ______________________ on ______________________, 2004.

____

Ashok Lahiri

(4) Signed at ______________________ on ______________________, 2004.

____

Ian R. McFadyen

(5) Signed at ______________________ on ______________________, 2004.

____

Bruno Michel

(6) Signed at El Salto, Jalisco, MEXICO on 21 July, 2004.

Mark C. Thurber

Mark C. Thurber